

EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S188	5903	(438/14,18,108,763).OCLS.	USPAT; USOCR	OR	OFF	2012/03/03 22:59
S189	1138	S188 and (sputtering or ion adj milling)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2012/03/03 22:59
S190	258	S189 and (semiconductor and cleaning)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2012/03/03 22:59
S191	1992	(semiconductor with (wafer or substrate) with (test\$3 or prob\$3)) and ((ion milling) or (sputter\$3 with etch\$3))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2012/03/03 22:59
S192	1091	S191 and @ad<"20040225"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2012/03/03 22:59
S193	157	S192 and (((ion milling) or (sputter etch\$3)) and (testing or probing or test or probe\$1) with wafer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2012/03/03 22:59
S194	5903	(438/14,18,108,763).OCLS.	USPAT; USOCR	OR	OFF	2012/03/03 23:00
S195	1138	S194 and (sputtering or ion adj milling)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2012/03/03 23:00
S196	258	S195 and (semiconductor and cleaning)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2012/03/03 23:00
S197	156	S196 and @ad<"20040225"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2012/03/03 23:00
S198	65	S197 and (argon or Ar or helium or He or neon or Ne)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2012/03/03 23:00

EAST Search History (Interference)

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3/ 5/ 2012 11:58:19 PM

**C:\Users\bau\Documents\EAST\Workspaces\Metallization\Electrical Contacts\10786807
bumps made of gold and its cleaning using ion milling before probing.wsp**